

<b>Notice of References Cited</b>	Application/Control No. 10/684,930	Applicant(s)/Patent Under Reexamination QUICK, NATHANIEL R.	
	Examiner Igwe U. Anya	Art Unit 2825	Page 1 of 1

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	C	US-6,670,693	12-2003	Quick, Nathaniel R.	257/588
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	L	US-			
	M	US-			

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**NON-PATENT DOCUMENTS**

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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.